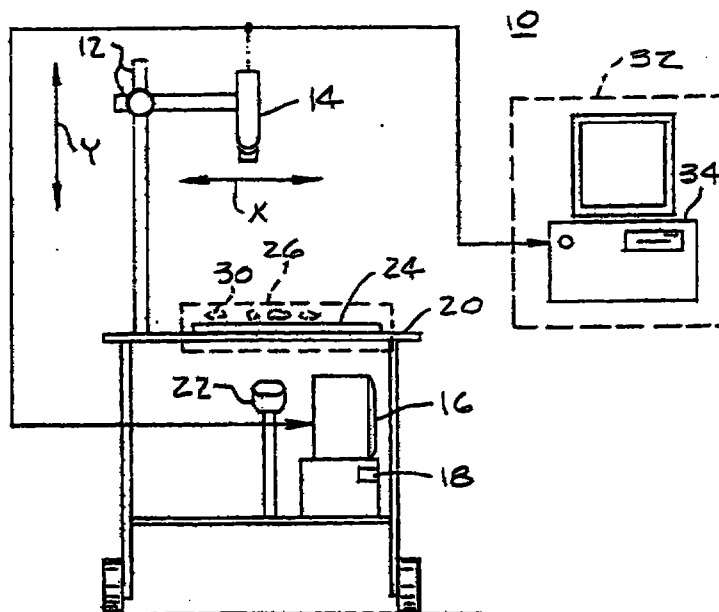




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(54) Title: METHOD AND SYSTEM FOR MEASURING POLYCRYSTALLINE CHUNK SIZE AND DISTRIBUTION IN THE CHARGE OF A CZOCHRALSKI PROCESS

**(57) Abstract**

A method and system for determining polycrystalline silicon chunk size for use with a Czochralski silicon growing process. Polycrystalline silicon chunks are arranged on a measuring background. A camera captures an image of the chunks. An image processor processes the image and determines the dimensions of the chunks based on the captured image. A size parameter associated with the chunks is determined.